

Notice of References Cited	Application/Control No. 09/942,731	Applicant(s)/Patent Under Reexamination TAKAHASHI ET AL.	
	Examiner Steven H. Rao	Art Unit 2814	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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	B	US-6,118,516	09-2000	Irie et al.	355/53
	C	US-5,602,679	02-1997	Dolgoff et al.	359/640
	D	US-2002/0036731	03-2002	Takahashi et al.	349/112
	E	US-2003/0076423	04-2003	Dolgoff, Eugene	348/222.1
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	G	US-2003/0197906	10-2003	Furuta et al.	359/15
	H	US-2003/0151784	08-2003	Kitamura et al.	359/3
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NON-PATENT DOCUMENTS

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✓	U	Ronald W. Waynant and Marwood N. Ediger " Electro-Optics hand book (McGraw-Hill) , pp.2.14-2.17 (1994) (copies given to AR Olenginski at interview)
✓	V	Gregory p. Behrmann et al., " Excimer laser micromachining for rapid fabrication of diffractive optical elements " Applied optics, Vol. 36, No. 20, July 10, 1997.(copies given to AR Olengenskia t interview)
✓	W	E. Pawlowski " Thin film depostion: an alternative technique for the fabrication of bianry optics with high efficiency" (copies given to AR Olengenski at interview).
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.